



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihito Tsuga, et al. Docket No: TI-31620  
Serial No: 10/085,753 Conf. No: 8409  
Examiner: Michail Kornakov Art Unit: 1746  
Filed: 02/28/2002  
For: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

AMENDMENT UNDER 37 C.F.R. § 1.111

RECEIVED  
DEC 11 2003  
TC 1700

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)  
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 12-3-03.

Ann Trent  
Ann Trent

Dear Sir:

Responsive to the Office Action mailed October 27, 2003, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.